

# **The Proton Source for the European Spallation Source (PS-ESS): installation and commissioning at INFN-LNS**

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**ESS** groups: *Control System, Beam Diagnostics, Vacuum, and Beam Physics*

**CEA** (ESS subcontractor for Control System and Beam Diagnostics)

**Si.a.tel.** (INFN & ESS control system subcontractor): S. Di Martino, P. Nicotra

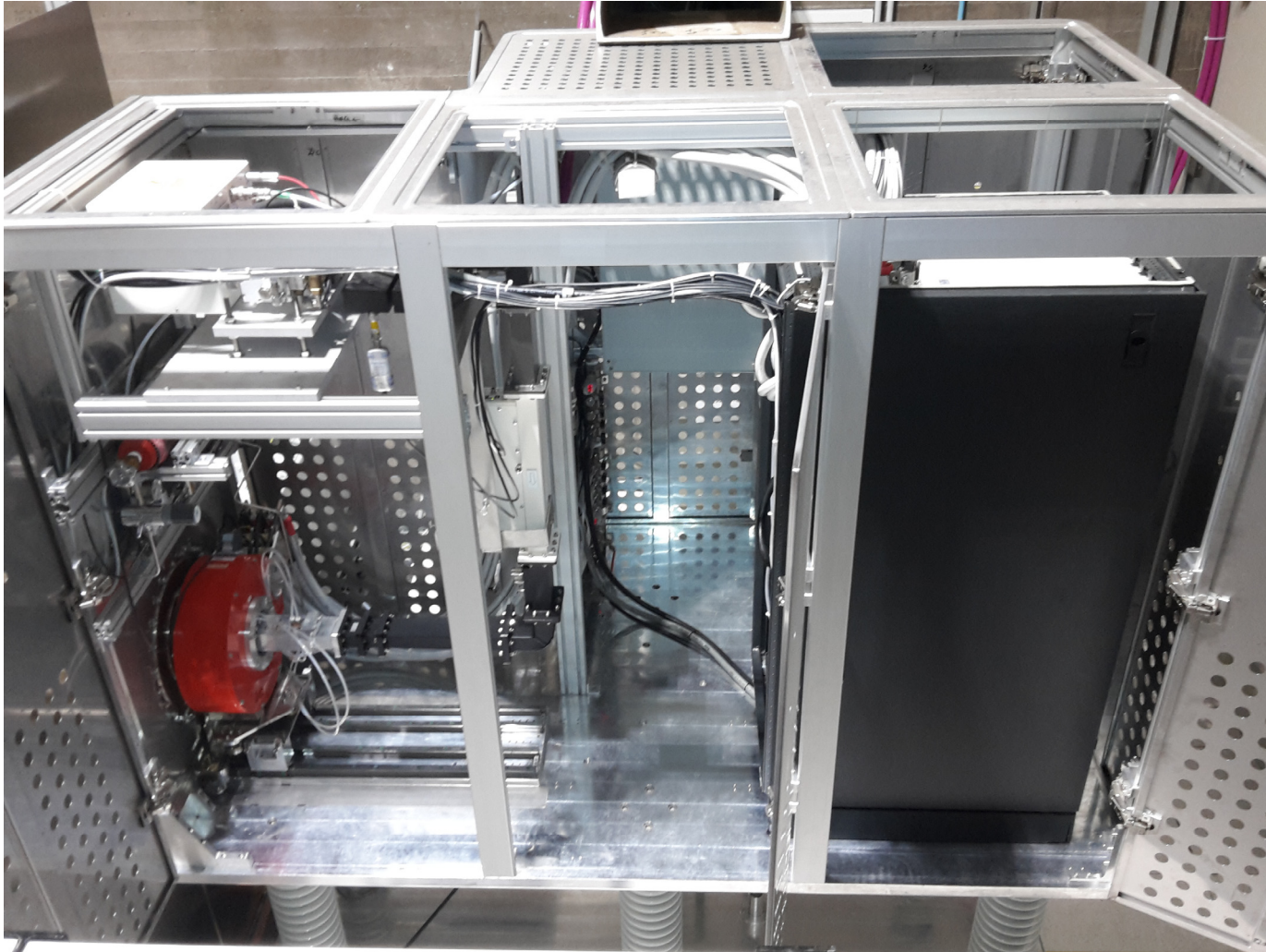
# PS-ESS and LEBT

05/08/2016



# PS-ESS and LEBT

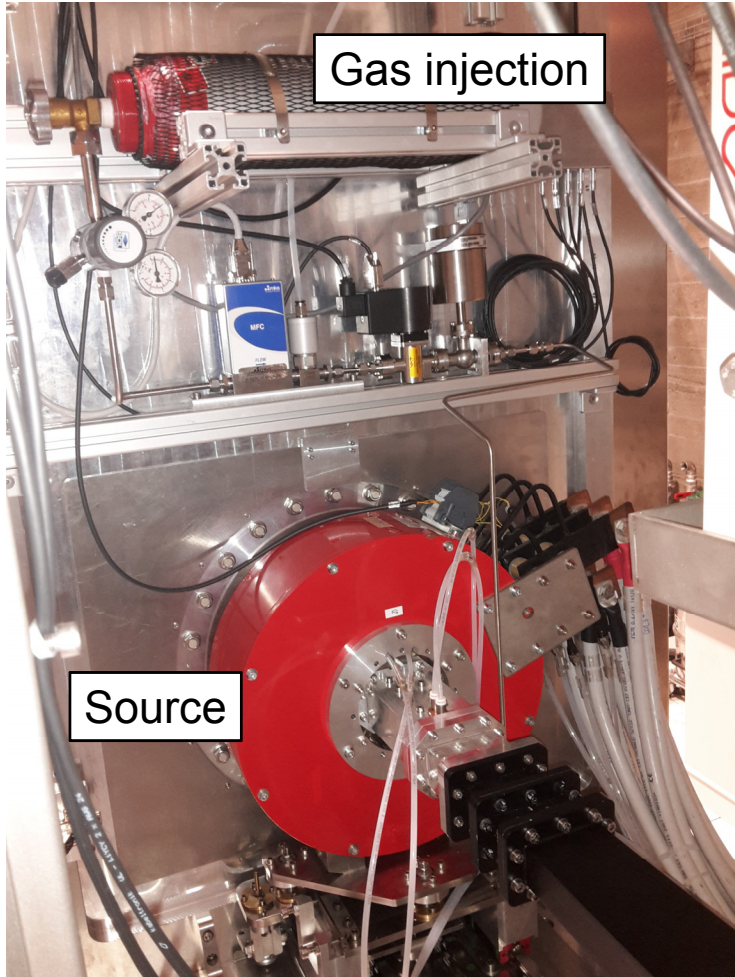
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HV platform fully assembled and cabled  
Control system will be installed in September

# PS-ESS and LEBT

05/08/2016



## HV rack



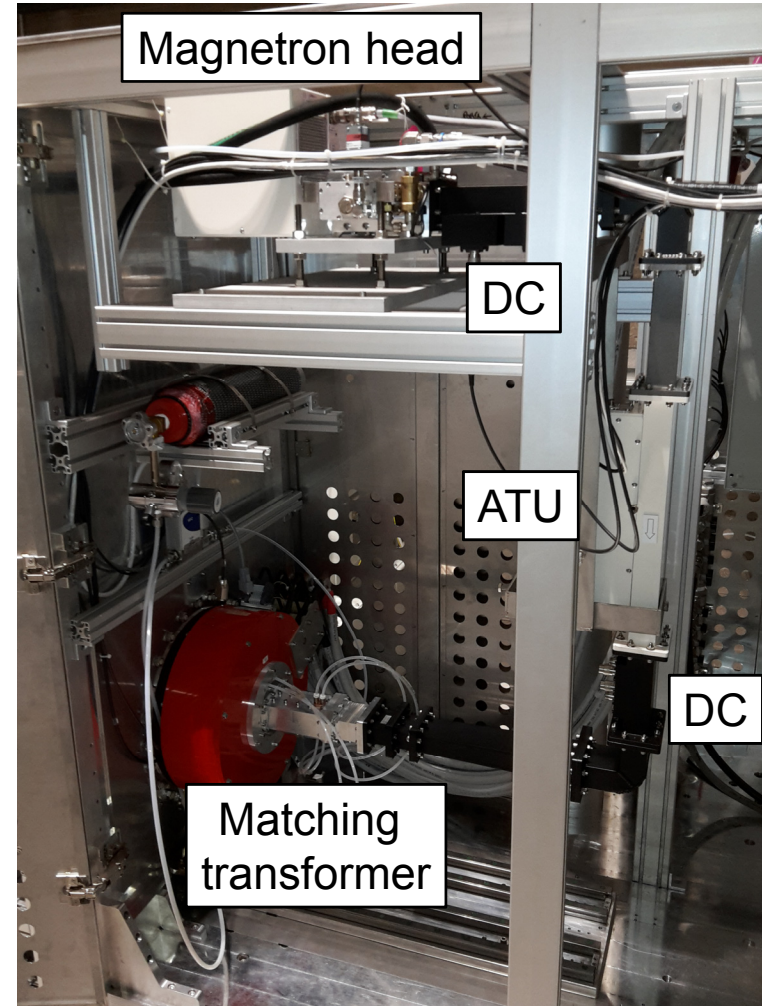
3 x power supplies  
for the magnetic  
system

Magnetron fast  
shutdown unit

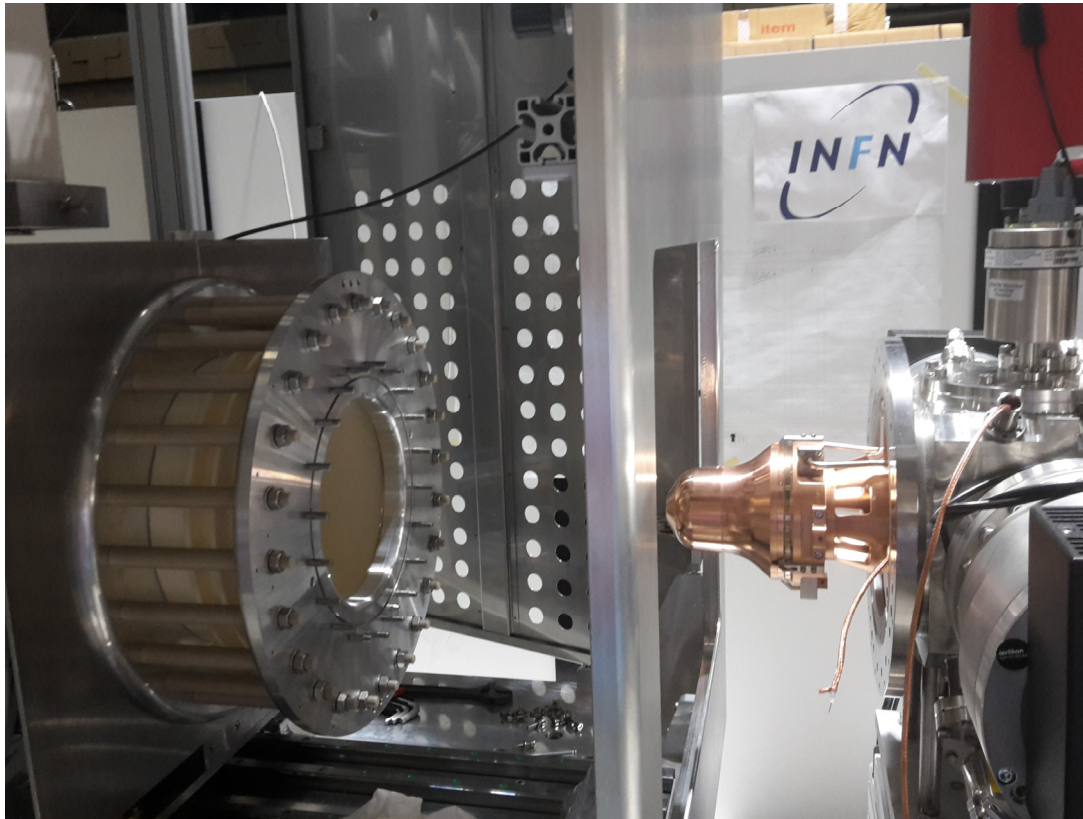
Magnetron

Vacuum controller  
unit

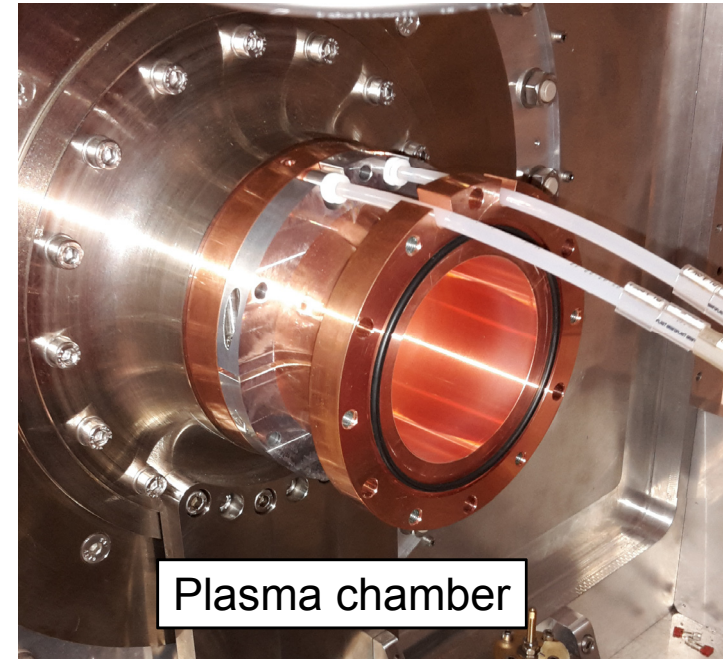
Shielded sub-rack  
for controls



# PS-ESS details



Design was optimized for easy and fast maintenance operation  
(Poster WEPP15)

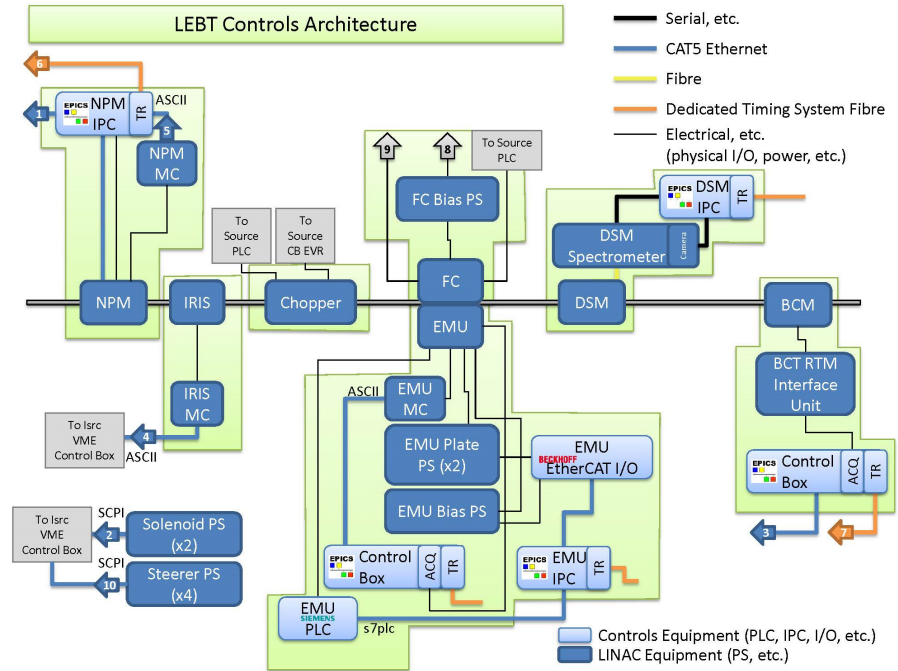
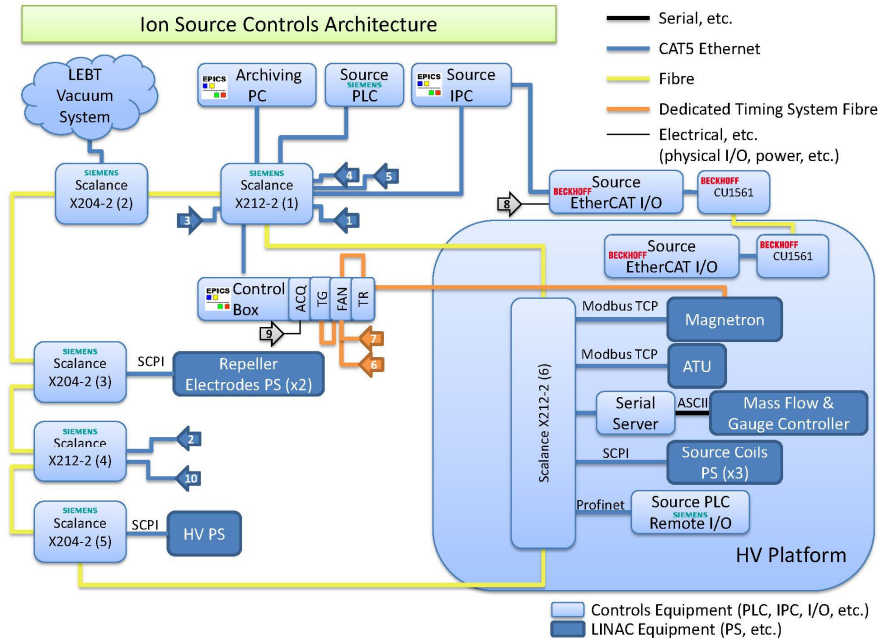


Plasma chamber



Matching transformer

# Control system



- Architecture ✓ done
- PLC ✓ done
- Ethercat I/O ✓ done
- EMC protection ✓ done
- Schematics ✓ done
- Cabling at HV ✓ done
- Cabling at ground ✓ 02/09/2016
- EPIC drivers ✓ done
- GUI ✓ In progress
- Software installation ✓ 30/09/2016



# Racks layout

PDU	
MOXA Box	
HMI (FUTURE USE)	
VEG-10010 MKS937b	VEVMC-10010 MKS946
VEG-20020 MKS937B	VEVMC-20020 MKS946
VEPT-02100 TD20	VEPT-03100 TD20
VEPT-06100 TD20	VEPT-07100 TD20
VEPP-00010 PRIMARY PUMP CONTROLLER	
IPC	

Repeller Electrode PS FUG HCP 35-3500	Repeller Electrode PS FUG HCP 35-3500
Solenoids Power Supply SORENSEN SGA 30X501D-2GAA	
Solenoids Power Supply SORENSEN SGA 30X501D-2GAA	
Steerer H1 PS Sorensen XG 12.5-120 MEB	
Steerer V1 PS Sorensen XG 12.5-120 MEB	
Steerer H2 PS Sorensen XG 12.5-120 MEB	
Steerer V2 PS Sorensen XG 12.5-120 MEB	
Siemens Scalanc oe X204-2 (3)	Siemens Scalance X212-2 (4)

Source Control Box Industrial PC Nexcom NISE 3600E		
Source Control Box VME Crate (with additional cards)		
IRIS Motion Control Geo Brick LV IMS II		
IRIS Motion Control PS		
NPM Control Box Industrial PC Kontron KISS 2U Short KTQ87		
NPM Motion Control Geo Brick LV IMS II		
NPM Motion Control PS		
MPS Interlock Box 1		
MPS Interlock Box 2		
FC Bias Power Supply ISEG THQ 2CH 2HE 60W		
ACCT-E RTM Interface Unit		
BCM Control Box microTCA.4 Crate		
Source PLC Central Node Siemens S7-1500		
Terminals, relays	Source GND EtherCAT Fan I/O Hub	Siemens Scalance X212-2 (1)

High Voltage Switcher Tirroir Basculeur	
EMU Control Box Industrial PC Nexcom NISE 3600E	
EMU PLC Siemens S7- 1500 PLC	Fast I/O Beckhoff ES3xxx Series
Duct	
Terminals	
Duct	
EMU Bias Power Supply ISEG THQ 2CH 2HE 60W	
EMU Motion Control Geo Brick LV IMS II	
EMU Motion Control PS	
EMU Plates Power Supply Trek 609E-6	
EMU Plates Power Supply Trek 609E-6	
EMU Control Box VME Crate (with additional cards)	



Racks at ground are in the final position

EMUs rack will arrive 02/11/2016

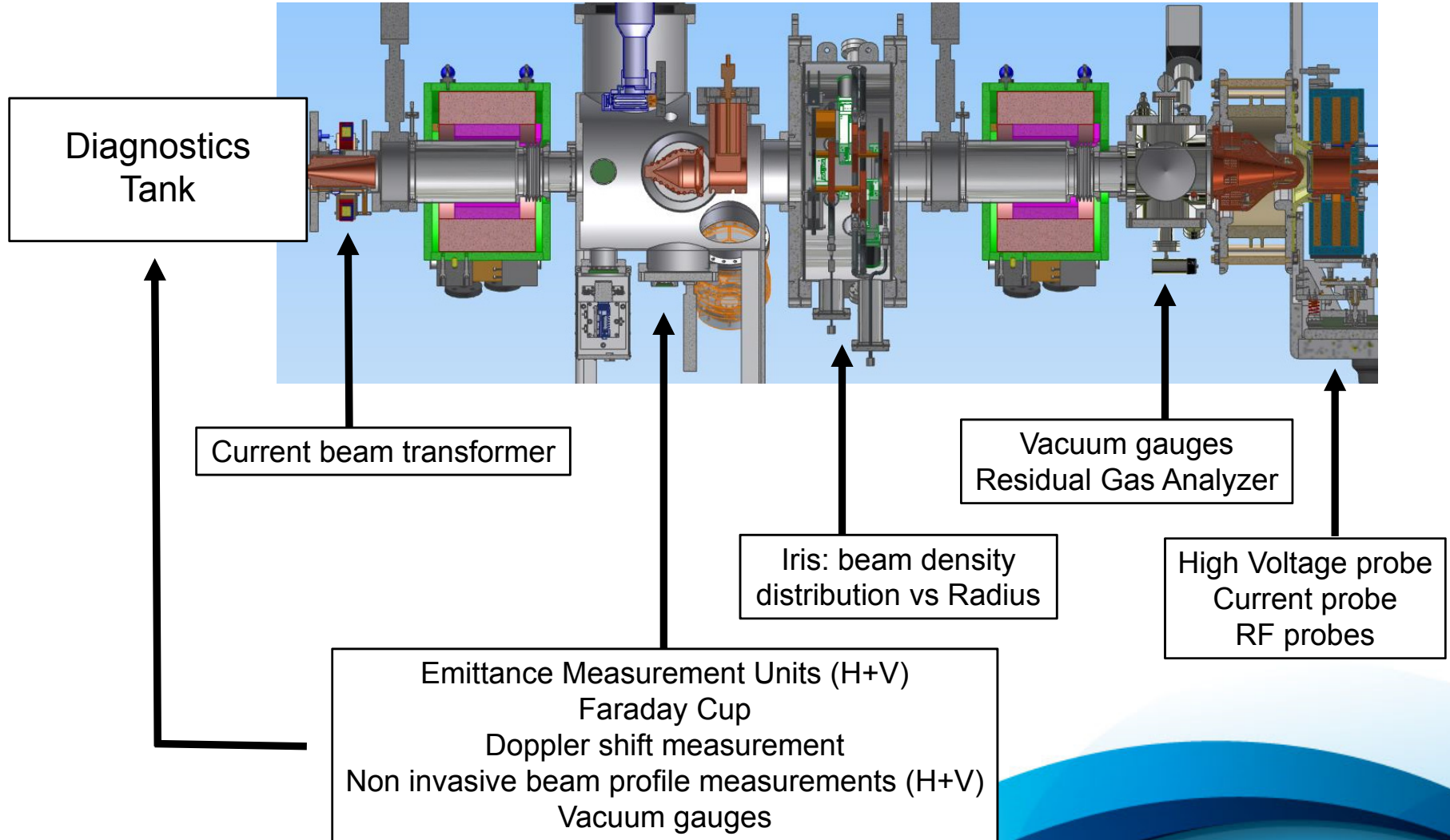
Vacuum

Power  
supplies

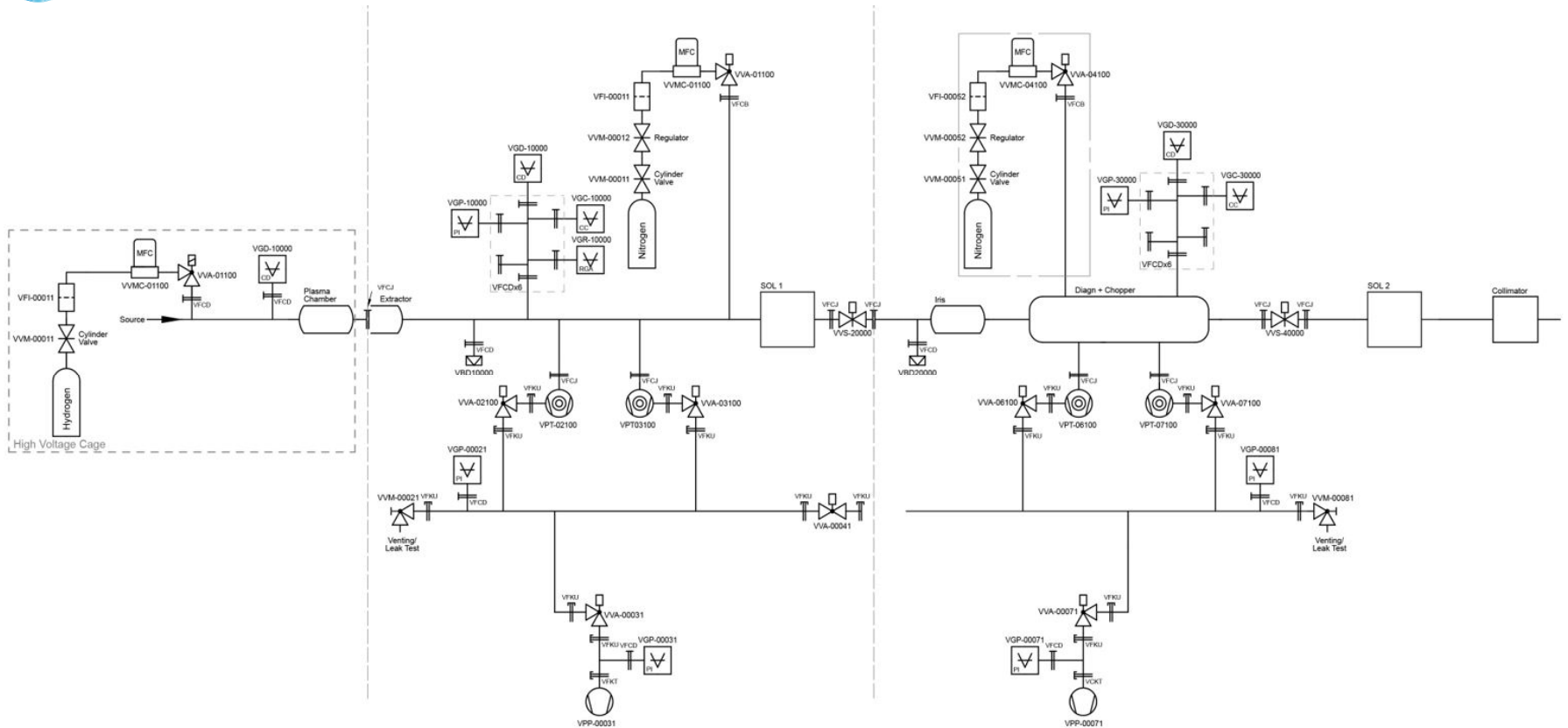
Diagnostics  
& Controls

EMUs

# Beam diagnostics



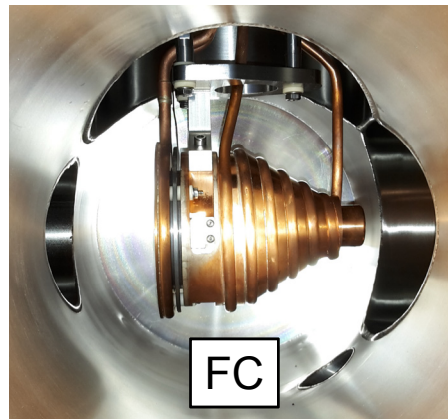
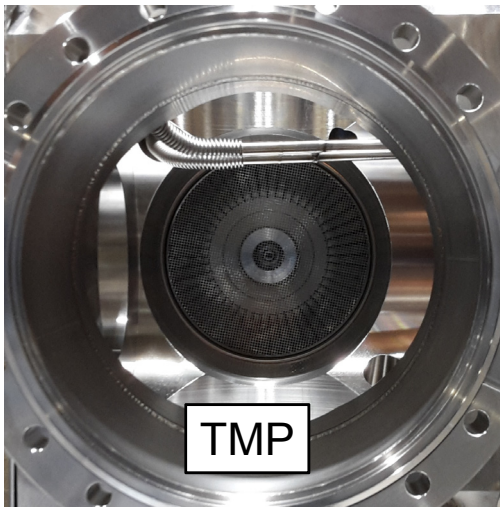
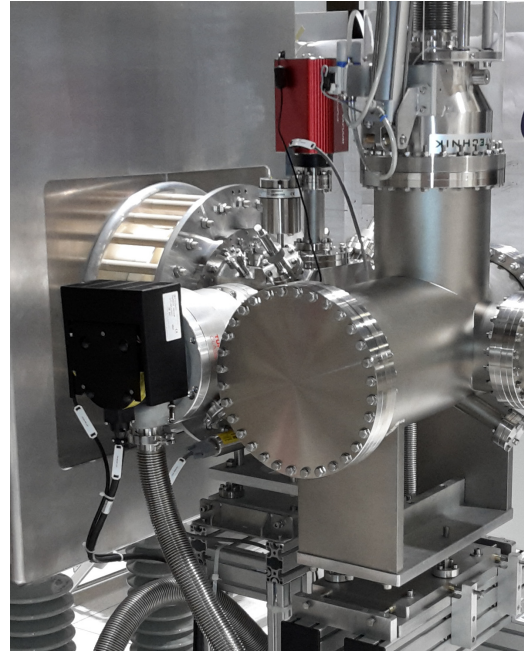
# Vacuum layout



- |                                |                                  |
|--------------------------------|----------------------------------|
| 2 x Primary pumps              | 6 x Pirani gauges                |
| 4 x Turbo molecular pumps      | 2 x Cold cathode gauges          |
| 3 x Mass flow controllers      | 3 x Capacitive gauges            |
| Hydrogen bottle for the source | 2 x Burst disk                   |
| Nitrogen bottle for the LEBT   | 2 x Gate valves in the beam pipe |
| Residual Gas Analyzer          |                                  |

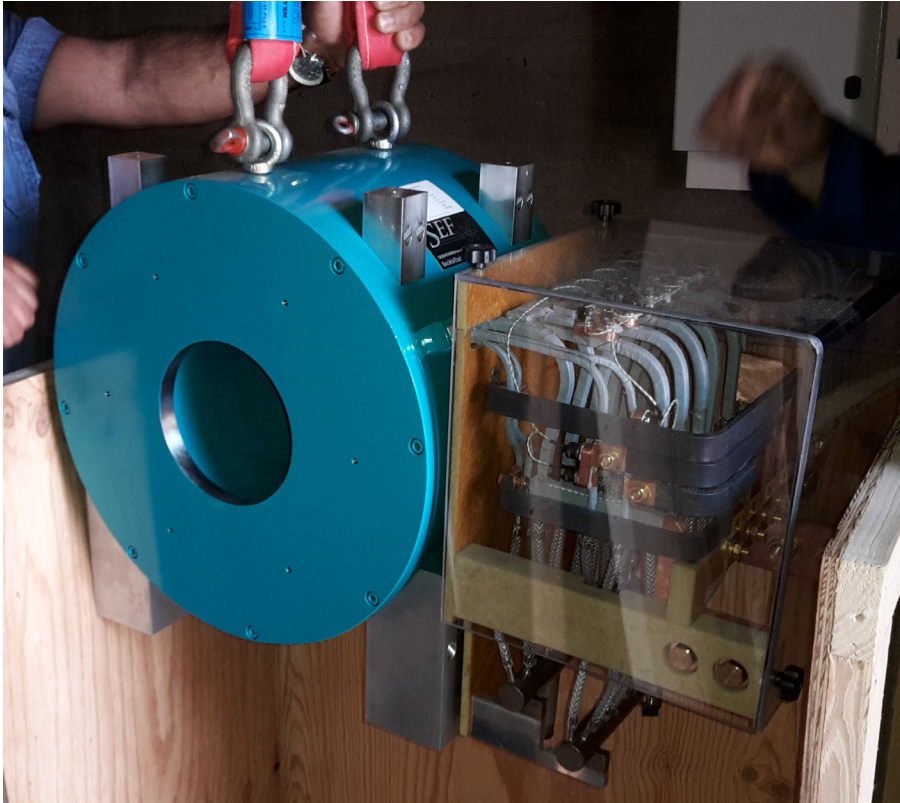
# LEBT ready for beam commissioning phase 1 & 2

- Extraction system
- Insulating column
- Extraction cooling
- 2 x TMP
- Gauges
- RGA
- FC
- Beam stop
- Valves
- Primary pump

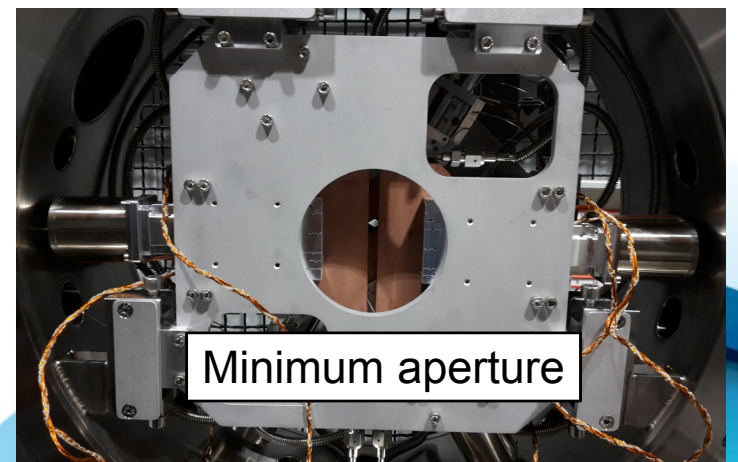
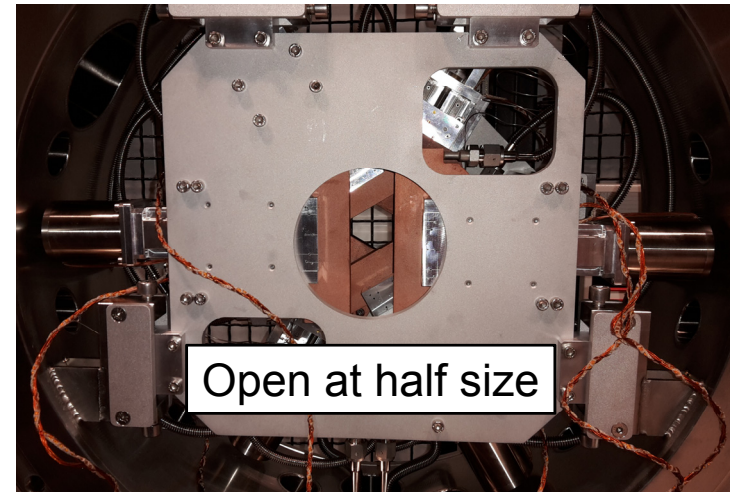


# Preparation for next commissioning phases

Two LEBT solenoids with integrated steerers were delivered



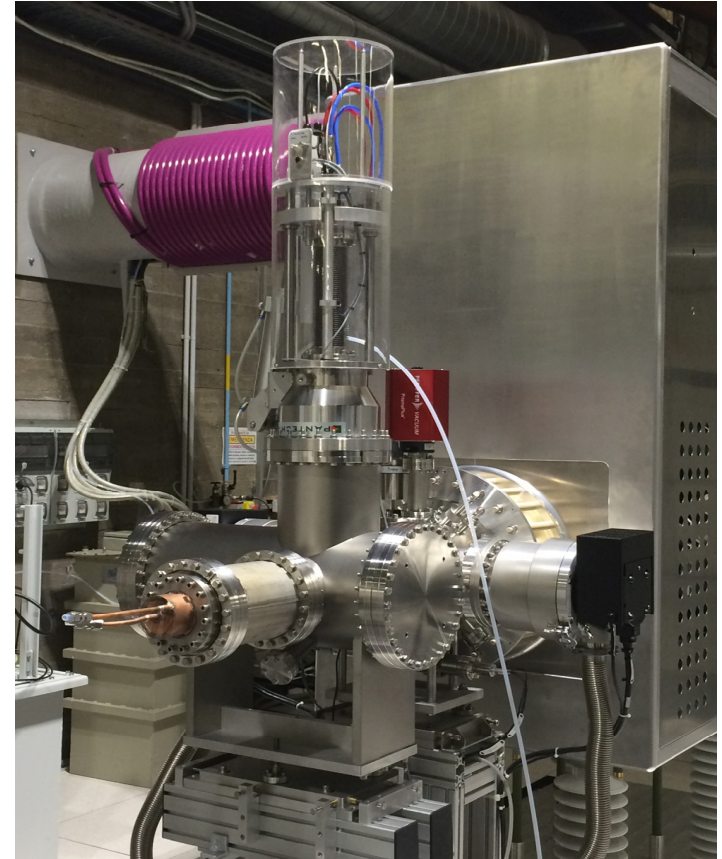
Iris mechanics, motors and controls are almost ready



# Phase 1: IS with FC and DSM

## Phase 2: Phase 1 + EMU

Beam performance	Value	Measurement device
Maximum beam current	> 90 mA	FC
Nominal proton beam current	74 mA	FC
Pulse length	3 ms	
Pulse length maximum	6 ms	
Flat top stability	$\pm 2\%$	
Pulse to pulse stability	$\pm 3.5\%$	
Repetition rate	14 Hz	
Repetition rate range	1-14 Hz, 1 Hz step	
Pulse length range	1 ms - 3 ms	
Recovery after 5 s downtime	1 pulse	DSM
Proton fraction	> 75 %	
Beam energy	75 keV	HV power converter
Beam energy fluctuation	$\pm 0.01$ keV	
Energy adjustment range	$\pm 5$ keV	
Energy adjustment precision	$\pm 100$ eV	EMU
Transverse emittance (99 %) at IS-LEBT lattice interface	1.8 $\mu\text{m}$	
Beam divergence (99 %) at IS-LEBT lattice interface	80 mrad	
Beam alignment at solenoid 1	$\pm 0.5$ mm	
Beam center offset at IS-LEBT lattice interface	$\pm 0.1$ mm	
Beam angle offset at IS-LEBT lattice interface	$\pm 1$ mrad	

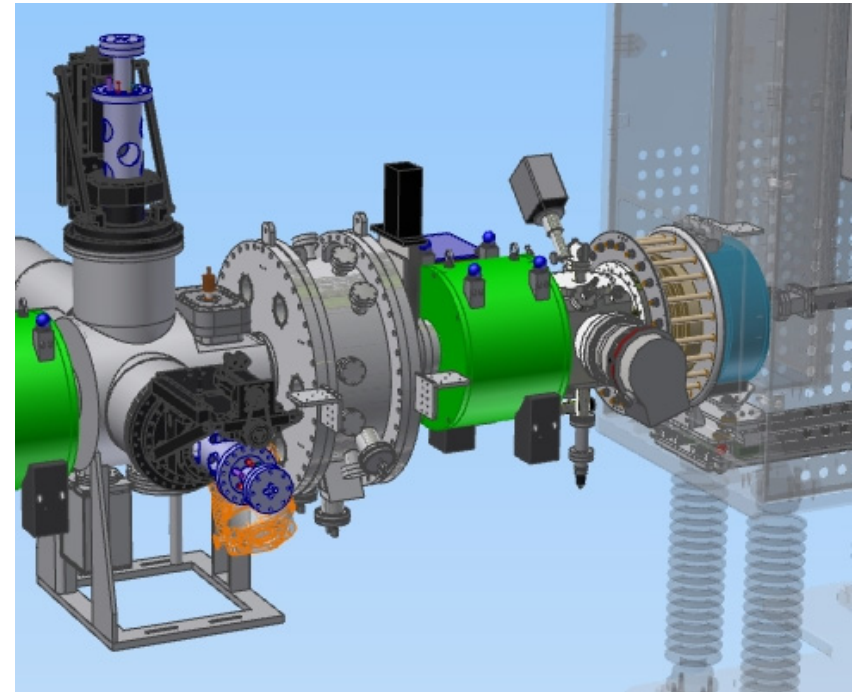


### Study of different parameters:

- Insulating/conductive plasma walls
- Magnetic configuration
- Extraction geometry
- Gas injection
- Pressure

# Phase 3: beam characterization after the first solenoid

Beam performance	Value	Measurement device
Beam current range	7-74 mA	Faraday cup
Beam current range step size	2 mA	
Beam current precision	$\pm 1$ mA	
Orbit control with respect to beam axis	$\pm 0.5$ mm	NPM
Transverse emittance	–	EMU
Beam center offset	–	
Beam angle offset	–	

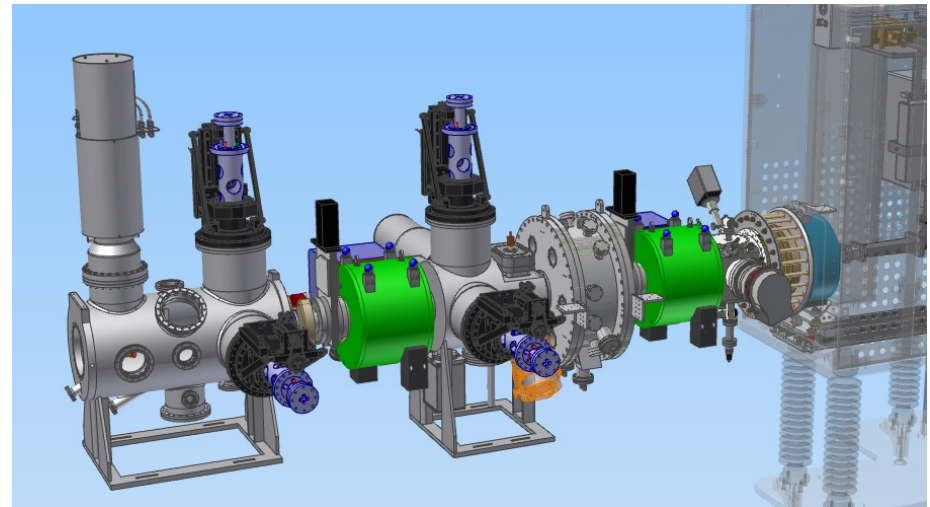


### Study of different parameters:

- Addition LEBT gas injection
- LEBT pressure
- Solenoids configuration
- Repelling electrodes voltage

# Phase 4: beam characterization at the LEBT-RFQ lattice interface

Beam performance	Value	Measurement device
Nominal beam current	74 mA	ACCT / Faraday cup
Beam current transmission	95 %	
Pulse length	2.86 ms	
Maximum pulse length	2.88 ms	
Pulse length range	0.005–2.88 ms	
Single pulse production	–	
Transmission of transient	>1 %	
Transverse emittance (norm, rms) at LEBT-RFQ lattice interface	0.25 $\mu\text{m}$	EMU
Transverse emittance (99 %) at LEBT-RFQ lattice interface	2.25 $\mu\text{m}$	
Beam alignment at LEBT-RFQ lattice interface	$\pm 0.1$ mm	
Transverse twiss $\alpha$ at LEBT-RFQ lattice interface	$1.02 \pm 20$ %	
Transverse twiss $\beta$ at LEBT-RFQ lattice interface	$0.11$ mm $\pm 10$ %	



### Study of different parameters:

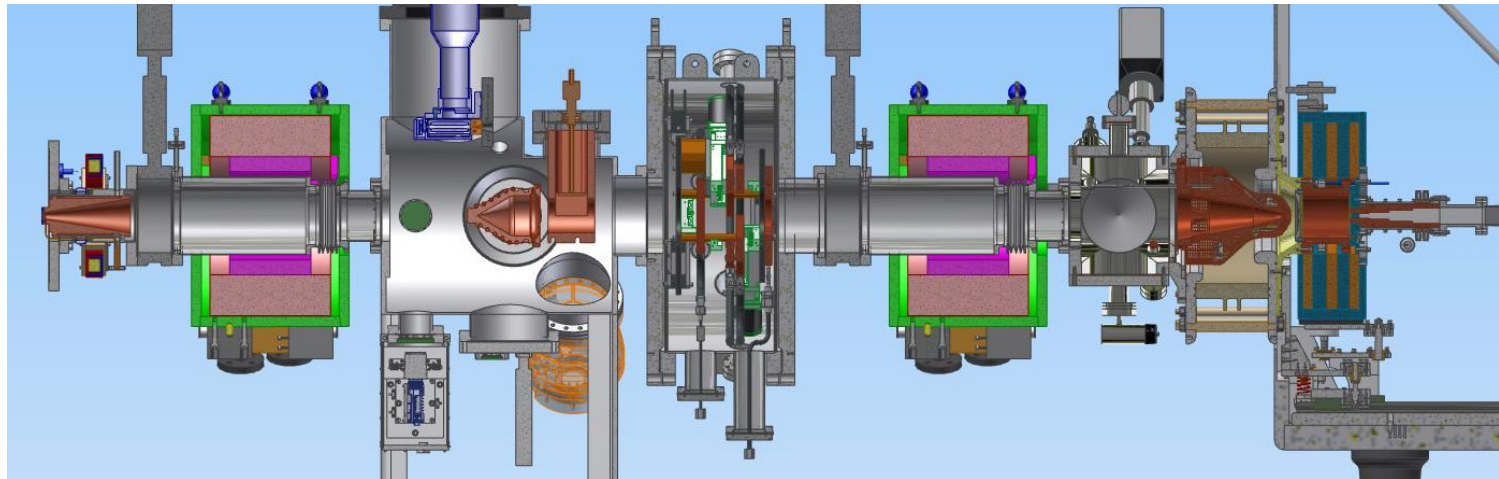
- Addition LEBT gas injection
- LEBT pressure
- Chopper voltage and rise/fall time speed
- Solenoids configuration
- Repelling electrodes voltage



## Phase 5: long duration tests (to be completed after RFI)

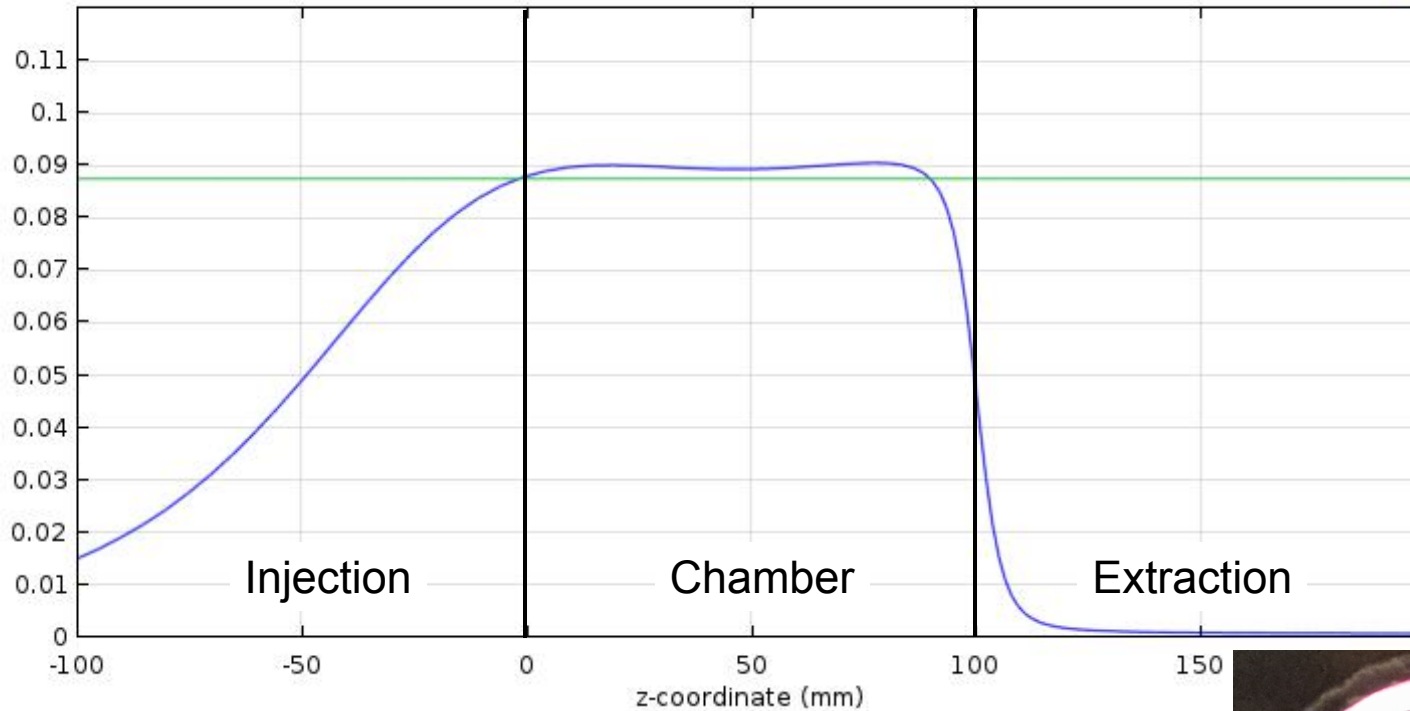
Consists of several tests:

- study the long-term reliability of the ion source and define which parts get degraded over time,
- study the current range that can be produced by the ion source (6-74 mA, ISrc.SyR-13),
- analyze potential beam trips to evaluate and prevent downtime,
- define a sequence for an automatic start-up of the ion source,
- simulate the time needed to restart the ion source after shut down (16 hours, ISrc.SyR-14),
- simulate the time needed to restart the ion source after maintenance, such as replacing the boron nitride disks (32 hours, ISrc.SyR-15),
- ensure that the different beam requirements can be satisfied at the same time (ISrc.SyR-22, LEBT.SyR-20),
- improve the design (for example of the extraction system) and ion source and LEBT settings to ensure that the requirements settled are satisfied.



# First plasma 15/06/2016

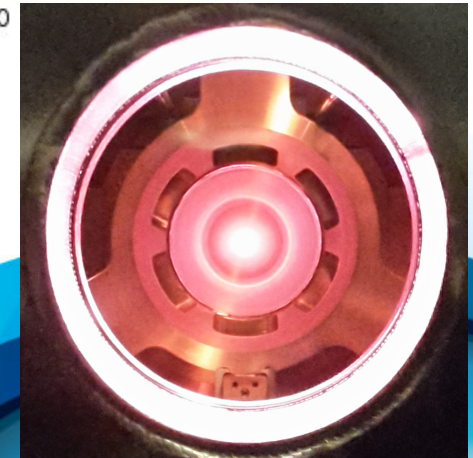
Line Graph: Magnetic flux density norm (T) Line Graph: 0.0875 (1)



H<sub>2</sub> flow 0.7 sccm | RF power up to 380 W

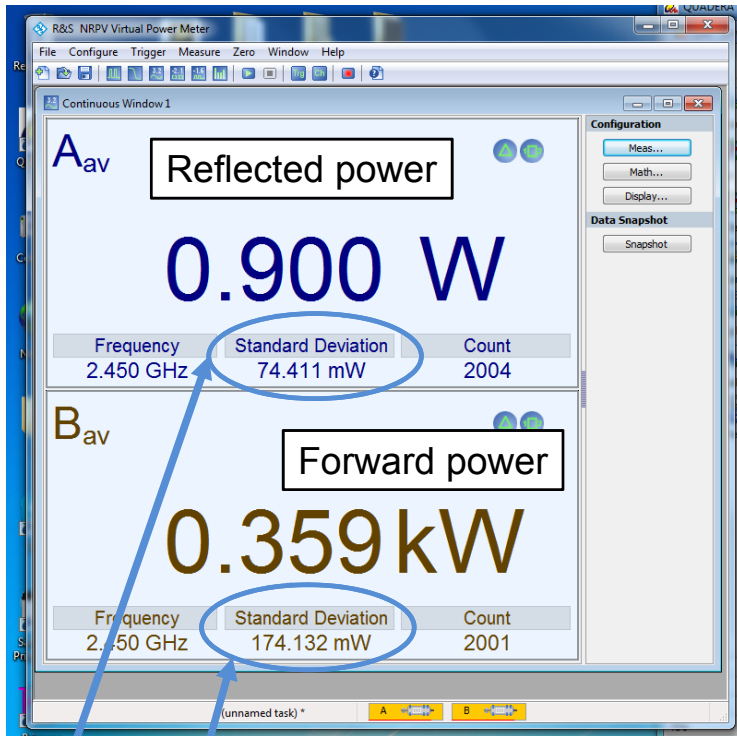
LEBT background pressure  $1.8 \cdot 10^{-6}$  mbar

LEBT pressure  $8.9 \cdot 10^{-6}$  mbar with plasma



# Measurement of RF power to plasma matching

Software interface of the two RF probes



Standard Deviation

Directional couplers

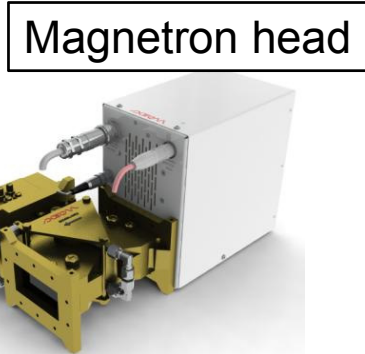
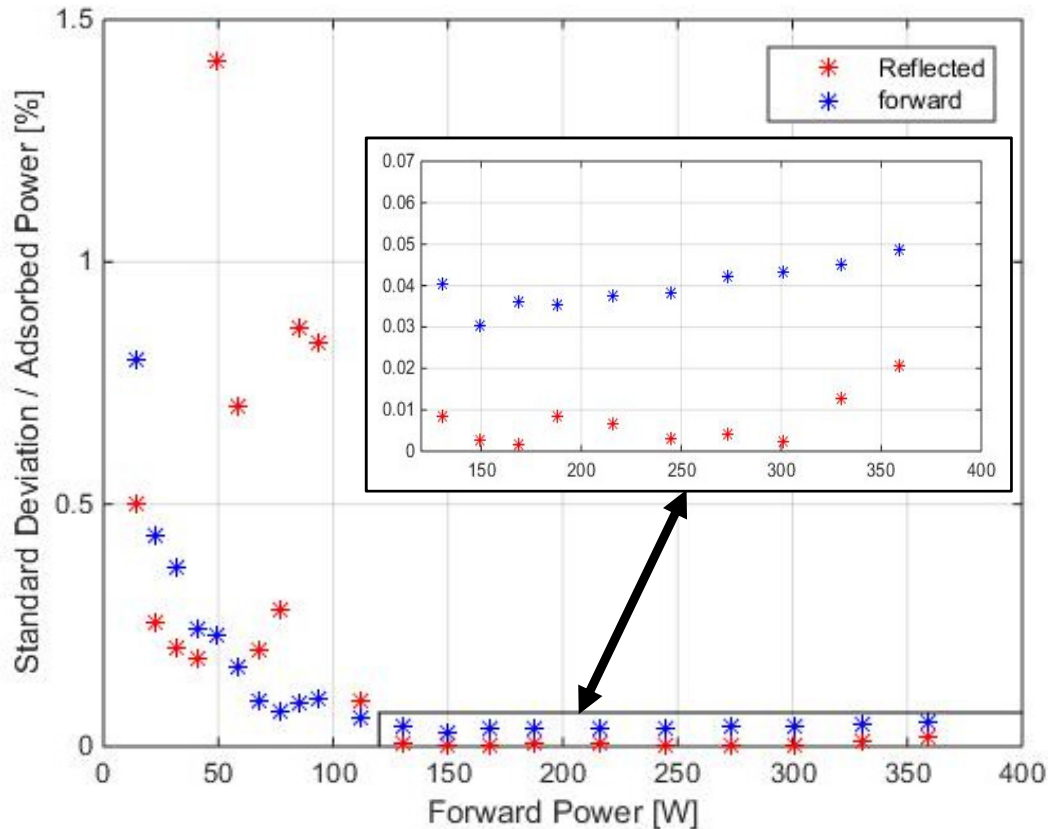
RF probes



First plasma  
15/06/2016



# Extremely high stability of adsorbed RF power



Plasma stability is not enough to predict that beam stability will be in the required range of  $\pm 2\%$ , but it is a good starting point to be optimistic.

Frequency	2450 MHz $\pm$ 25 MHz
Output power	2 kW with 10 W step
Power stability	1 %
Ripple	< 1 % RMS

# Conclusion

## PS-ESS and LEBT:

- The source is fully assembled
- The LEBT for the first two commissioning phases is ready
- The cabling is almost finished
- The software will be installed in September
- Commissioning plan is defined
- Plasma conditioning started
- Excellent RF to plasma coupling and stability was observed